



520.43302PX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Akira HAMAMATSU et al.

Serial No.: 10/724,750

Filed: December 2, 2003

Title: METHOD FOR INSEPCTING DEFECT  
AND APPARATUS OR INSPECTING DEFECT

Group: 2877

Examiner: STAFIRA, Michael Patrick

Confirmation No.: 2088

**AMENDMENT**

**Mail Stop: AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

January 25, 2007

Sir:

In response to the Office Action dated September 25, 2006, the period of response for which extension of time is requested in the attached Petition for Extension of Time, please amend the above-identified application as listed below and as set forth on the following pages:

**Amendments** to the claims begin on page 2;

**Remarks** are included beginning on page 7; and

**Authorization** is included on page 9.